

Specialist for Dual-Beam Focused Ion Beam (FIB)

General description:

The Dual-Beam FIB system (Thermo Fisher Helios G4 UC) employs a focused Ga ion beam for site-specific material removal, with an electron beam thus providing a non-destructive imaging of the exposed sub-surface features.

This instrument is used for preparing three dimensional structures and devices at the nanometer scale, spans a wide range of applications such as preparation of TEM lamella, device fabrication, characterization of thin films, cross sectioning and tomography.

The Dual-Beam FIB is located at the [Tel Aviv University Center for Nanoscience and Nanotechnology](#), which serves as a central university user facility for researchers from Life Sciences, Exact Sciences and Engineering.

The FIB specialist is expected to be responsible for operating and maintaining the Helios G4 UC system, to become an expert, and to bring her/his invaluable expertise for supporting the research community at TAU.

Responsibilities:

- Operation of state-of-the-art Dual Beam FIB
- Research support for the TAU research community as well as customers from external academic institutions and industry
- Training of students to become independent users
- Responsibility for maintenance and running operation of the lab

Required qualifications:

- Ph.D. degree in Materials Engineering, Physics, Chemistry or related field
- Expertise in Scanning Electron Microscopy (preferably)
- Hands-on materials characterization experience
- Technical proficiency in applying complex research instrumentation to solve research problems
- Research oriented, curiosity driven
- Motivated independent thinker with problem-solving skills
- Team player, ability to multi-task and work cooperatively with others

Please contact the Managing Director of the Tel Aviv University Center for Nanoscience and Nanotechnology, [Alice Polacsi-Segev](mailto:alicepolacsi@tauex.tau.ac.il), alicepolacsi@tauex.tau.ac.il, 03-6407926